	Application No.	plication No. Applicant(s)	
Notice of Allowability	09/662.682	LI ET AL.	\
	Examiner	Art Unit	
	Lan Vinh	1765	(0)
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The MAILING DATE of this communication appe All claims being allowable, PROSECUTION ON THE MERITS IS herewith (or previously mailed), a Notice of Allowance (PTOL-85) NOTICE OF ALLOWABILITY IS NOT A GRANT OF PATENT RI	(OR REMAINS) CLOSED i or other appropriate comm IGHTS. This application is	n this application. If not inclu- unication will be mailed in du-	ded e course. THIS
1. Applicants' s remarks	filed on 10/7/2003.		
2. The allowed claim(s) is/are 1-21.			
3. The drawings filed on 15 September 2000 are accepted by	the Examiner.		
4. Acknowledgment is made of a claim for foreign priority un	nder 35 U.S.C. § 119(a)-(d)	or (f).	
a) All b) Some* c) None of the:			
1. Certified copies of the priority documents have			
2. Certified copies of the priority documents have			
3. Copies of the certified copies of the priority do	cuments have been receive	d in this national stage applic	ation from the
International Bureau (PCT Rule 17.2(a)).			
* Certified copies not received: 5. Acknowledgment is made of a claim for domestic priority un reference was included in the first sentence of the specifical			ce a specific
(a) The translation of the foreign language provisional a	• •		
 Acknowledgment is made of a claim for domestic priority up in the first sentence of the specification or in an Application 		or 121 since a specific refere	nce was included
Applicant has THREE MONTHS FROM THE "MAILING DATE" of below. Failure to timely comply will result in ABANDONMENT of	this communication to file at this application. THIS THE	a reply complying with the req REE-MONTH PERIOD IS NO	uirements noted TEXTENDABLE.
 A SUBSTITUTE OATH OR DECLARATION must be subm. INFORMAL PATENT APPLICATION (PTO-152) which give 			NOTICE OF
 CORRECTED DRAWINGS (as "replacement sheets") mus (a) ☐ including changes required by the Notice of Draftspers 		w (PTO-948) attached	
1) hereto or 2) to Paper No			
(b) ☐ including changes required by the proposed drawing c		• • • • • • • • • • • • • • • • • • • •	
(c) ☐ including changes required by the attached Examiner's	s Amendment / Comment o	r in the Office action of Paper	· No
Identifying indicia such as the application number (see 37 CFR 1. each sheet. Replacement sheet(s) should be labeled as such in the	84(c)) should be written on t he margin according to 37 Cl	he drawings in the front (not th FR 1.121(d).	ne back) of
DEPOSIT OF and/or INFORMATION about the deposit attached Examiner's comment regarding REQUIREMENT FOR THE COMMENT FOR THE POSITION AND ADMINISTRATION ADMINISTRATION ADMINISTRATION AND ADMINISTRATION ADMINISTRAT			Note the
Attachment(s)			
1 Notice of References Cited (PTO-892)	5∏ Notice of Inf	ormal Patent Application (PTG	O-152)
 Notice of Draftperson's Patent Drawing Review (PTO-948) Information Disclosure Statements (PTO-1449 or PTO/SB/08) Paper No 		mmary (PTO-413), Paper No	··
	7☐ Examiner's Amendment/Comment		
4 Examiner's Comment Regarding Requirement for Deposit of Biological Material	8⊠ Examiner's 9 9∏ Other	Statement of Reasons for Allo	wance
		Lan Vinh AU 1768	~

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Allowable Subject Matter

1. Claims 1-21 are allowed.

The following is an examiner's statement of reasons for allowance:

Regarding claims 1, 11, 21, the applicants have presented a persuasive argument that the cited prior art of record fails to disclose a method for producing porous silicon comprising the step of forming the porous silicon by etching the Si surface having a thin discontinuous layer of metal in a HF and oxidant solution / etching the Si surface having a thin discontinuous layer of metal in a HF and oxidant solution for a period of about two seconds up to 60 minutes, said etching being conducted without external electrical bias. The closest cited prior art of Lee et al (US 5,565,084) discloses an electropolishing method comprises the step of etching the porous Si surface having a thin layer of metal in a HF and oxidant solution while breaking the supply of the electricity/without external electrical bias for 1 minute after the step of forming the porous silicon by conducted an etching step with supplied electric current (col 4, lines 30-42)

Any comments considered necessary by applicant must be submitted no later than the payment of the issue fee and, to avoid processing delays, should preferably accompany the issue fee. Such submissions should be clearly labeled "Comments on Statement of Reasons for Allowance."

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Conclusion

 Any inquiry concerning this communication or earlier communications from the examiner should be directed to Lan Vinh whose telephone number is 571 272
 The examiner can normally be reached on M-F 8:30-5:30 PM.

If attempts to reach the examiner by telephone are unsuccessful, the examiner's supervisor, Nadine Norton can be reached on 571 272 1465. The fax phone number for the organization where this application or proceeding is assigned is (703) 872-9306.

Any inquiry of a general nature or relating to the status of this application or proceeding should be directed to the receptionist whose telephone number is 703 308-0661.

LV

January 2, 2004